

1.1 eV GalnAs Cell Development for Dual-use Solar and 1075 nm Laser Power Converters

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Introduction

-* Dual-use PV concept

- PV: Broad-spectrum energy conversion
- LPC: High-efficiency singlewavelength conversion

-* Benefits

- * Reduce solar panel area and required storage capacity of assets
- → Space applications: satellites, bases, rovers etc

-* Challenges

- Metamorphic cell growth, high temps, resistance losses

Single Junction Structure



- -* Inverted metamorphic
- → 1.1eV junction to target 1075nm laser
- Single junction
 - -* Buffer lavers removed
- -∗ Ga_{0.2}In_{0.8}As
- * Higher LPC efficiency, lower broadband efficiency

Triple Junction Structure

GalnF

1.9 eV

2.J

GaAs

14 eV

Buffer

3.1

GalnAs

1.1 eV

-* Triple junction → Addition of 1.4eV and 1.9eV junctions * Buffer layer not etched off -* Third contact to collect high current from laser Addition of third contact puts more emphasis on lateral current pathways (shown by blue arrows) which is highly dependent on sheet resistance



Single Junction Analysis

0.8

0.6

0.4

0.2

0.0

Solar Performance

- * QE shows broadband absorption of solar spectrum -* 1.1eV ideal for 1075nm
- wavelength (1.15eV) Characterized for AM0
- spectrum -* Without contact laver &
- buffer. GaInP window laver is still partially absorbing -* JV curve shows
- improvement to J_{ac} after removing buffer layer - Almost no effect to V

0.72

Acm

Density

ž

P) FF (%) Eff (%) 0.68 19.2 80.2 7.66

22.3 81.9 9.6



Quantum Efficiency





Laser Performance



0.0

1000 Wavelength (nm)

Triple Junction Analysis

Buffer Thickness Experiment

- -* GaInP graded buffer changes lattice constant to grow GalnAs on GaAs substrate
- -* In 1J. optimized buffer reduces threading dislocation densitv
 - Decreases non-radiative recombination
 - Increases V₀₀
- → In 3J. buffer serves also as a lateral transport to intermediate contact
- Sheet resistance is key
- Results show increasing buffer thickness decreases sheet resistance
- -* If buffer is too thick, cell quality decreases
- -* Optimal thickness around $5\mu m$





Sheet resistance vs. buffer thickness



Resistance Modeling

- Goal: Determine power loss given cell size
- -* Resistance values of interest
 - Sheet, contact, grid finger, base
- -* More grid fingers -> lower resistance loss -> more shadowing
- -* Optimal buffer thickness has sheet resistance of ~10 ohms
- Fabrication requires fingers only on cell perimeter







Summary

- -* 53% laser conversion efficiency achieved on lattice mismatched GaAs cell at 1075nm
- Buffer thickness optimized for cell quality in both 1J and 3J
- → Reduce threading dislocation in PN junction for 1J and 3J
- → Reduce sheet resistance for 3J
- -* Optimal grid finger spacing for cell is 0.2-1cm

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With buffer

n+ GalnP

n GalnAs

n GalnAs

p+ GalnP

After

buffer

n+ AllnP

n GalnP

p GalnP

D+ AlGala

LMM TJ

n+ GalnP

n GaAs

p GaAs

p+ GalnP

LMMTI

n+ GalnNAs

n+ GalnP

transparent graded buffer

n+ GaInP

n GalnAs

p GalnAs

p+ GalnP

removina

Cell Concepts

GaAs

substrate

(removed)

n+ GalnF

graded buffer

n+ GallnP

n GalnAs

p GalnAs

p+ GalnP